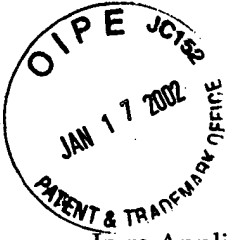


AF/1700  
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REPLY UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 1764

PATENT  
5480-00200/OP99140-US



Corres. and Mail  
BOX AF

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Kim

Serial No. 09/287,602

Filed: April 7, 1999

For: GAS SCRUBBER FOR TREATING  
THE GAS GENERATED DURING  
THE SEMICONDUCTOR  
MANUFACTURING PROCESS

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Group Art Unit: 1764  
Examiner: Varcoe, F.

Atty. Dkt. No. 5480-00200

I hereby certify that this correspondence is being deposited  
with the U.S. Postal Service with sufficient postage as First  
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11/20/01  
Date

Kevin L. Daffer

AMENDMENT; RESPONSE AFTER FINAL REJECTION  
PURSUANT TO 37 CFR § 1.116

Box: AF  
Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

RECEIVED  
JAN 22 2002  
TC 1700

This paper is submitted in response to the Office Action dated September 13, 2001 to  
further highlight reasons why the application is in condition for allowance.

Please amend the case as follows:

In the Claims:

Please replace claims 1, 6, 7, and 15 with the amended claims below. A "marked-up"  
version of each amendment is included in **Attachment A**.